

**In the Claims:**

Please amend the claims as follows:

1. (Currently Amended) Charged particle beam device, comprising  
an emitter array (22) for emitting a plurality of charged particle beams (8);  
a lens (42) for imaging the plurality of charged particle beams;  
an electrode unit (44) for accelerating the plurality of charged particle beams;  
a first control unit (44) and a second control unit (45) for controlling the potential differences between a first potential of the emitter array, a second potential of the electrode unit and a third potential of a specimen, wherein whereby the second potential is capable of accelerating the plurality of charged particle beams with respect to the first potential and whereby the third potential is capable of decelerating the plurality of charged particle beams with respect to the second potential.
2. (Currently Amended) The charged particle beam device of ~~according to~~ claim 1, wherein whereby the third potential is capable of defining the a charged particle beam energy on impingement of the plurality of charged particle beams on the specimen such that it corresponds to a potential of maximal 5 kV; and  
whereby the second potential is capable of increasing the charged particle beam energy to an energy that is at least a factor of 5 higher than the energy corresponding to the third potential.
3. (Currently Amended) The charged particle beam device of ~~according to~~ claim 1 ~~any of the preceding claims~~, further comprising:  
an extraction member (24) for extracting the plurality of charged particle beams.
4. (Currently Amended) The charged particle beam device of claim 1 ~~according to any of the preceding claims~~, further comprising;  
an emitting angle defining member (26) for controlling the emitting angle of the plurality of charged particle beams.

5. (Currently Amended) The charged particle beam device of claim 1 according to any of the preceding claims, wherein whereby the emitter array (22) is spaced from a specimen stage (18) by at least 10 mm, ~~preferably by at least 50 mm.~~

6. (Currently Amended) The charged particle beam device of claim 1 according to any of the preceding claims, further comprising a further electrode unit (32) biased to a potential which is capable of increasing the charged particle beam energy with respect to the energy corresponding to the third potential by at least a factor of 5.

7. (Currently Amended) The charged particle beam device of claim 1 according to any of the preceding claims, whereby, wherein the lens for imaging the plurality of charged particle beams (8) comprises a unit for providing a homogenous magnetic field (12', 42), wherein the unit for providing [[a]] the homogenous magnetic field comprises at least one coil (44).

8. (Currently Amended) The charged particle beam device of claim 7, wherein according to claim 6, whereby the unit for providing a homogenous magnetic field further comprises at least a second coil (46).

9. (Currently Amended) The charged particle beam device of claim 7, wherein according to any of claims 6 or 7, whereby the unit for providing a homogenous magnetic field further comprises at least one pole piece (48).

10. (Currently Amended) The charged particle beam device of claim 1, according to any of the preceding claims, further comprising a deflection system for deflecting the plurality of charged particle beams (8).

11. (Currently Amended) The charged particle beam device of claim 10, wherein according to claim 10, whereby the deflection system for deflecting the plurality of charged particle beams comprises a magnetic deflector (52) for deflecting the plurality of charged particle beams.

12. (Currently Amended) The charged particle beam device of claim 10, wherein ~~according to any of claims 10 to 11, whereby~~ the deflection system for deflecting the plurality of charged particle beams comprises a plurality of electrostatic deflectors (54) for individually deflecting the charged particle beams.

13. (Currently Amended) The charged particle beam device of claim 10, wherein ~~according to any of claims 10 to 12, whereby~~ the deflection system for deflecting the plurality of charged particle beams (8) comprises an electrostatic deflector for deflecting the plurality of charged particle beams.

14. (Currently Amended) The charged particle beam device of claim 6, wherein ~~according to any of the preceding claims, whereby~~ the electrode unit, (14) and/or the further electrode unit, (32) or both are ~~[[is]]~~ capable of providing a vacuum isolation.

15. (Currently Amended) The charged particle beam device of claim 14, wherein ~~according to claim 14, whereby~~ the vacuum isolation is provided by a transparency ratio between the area of apertures and the area of solid material of smaller than 1:100; ~~preferably smaller than 1:500, more preferably smaller than 1:10000.~~

16. (Currently Amended) The charged particle beam device of claim 1, wherein ~~according to any of the preceding claims, whereby~~ the third potential is capable of defining the charged particle beam energy on impingement of the plurality of charged particle beams on the specimen such that it corresponds to a potential of maximal 1 kV.

17. (Currently Amended) The charged particle beam device of claim 1, wherein ~~according to any of the preceding claims, whereby~~ the second potential is capable of increasing the charged particle beam energy to an energy that is at least a factor of 10 higher than the energy corresponding to the third potential.

18. (Currently Amended) The charged particle beam device of claim 7, wherein ~~according to any of claims 9 to 17, whereby~~ the unit for providing a homogenous

magnetic field further comprises a lower pole piece (~~48c, 49~~) which is movable with respect to the at least one pole piece (48).

19. (Currently Amended) The charged particle beam device of claim 1, wherein ~~according to any of the preceding claims, whereby~~ the charged particle device is a minicolumn.

20. (Currently Amended) Method of imaging a plurality of charged particle beams comprising ~~the following steps:~~

emitting the plurality of charged particle beams with an emitter array system;

focusing the plurality of charged particle beams on a specimen with a lens;

providing a first potential to the emitter array;

providing a second potential to an electrode unit such that the plurality of charged particle beams are accelerated;

providing a third potential to a specimen such that the plurality of charged particle beams are decelerated before impingement on the specimen.

21. (Currently Amended) Method of claim 20, wherein ~~according to claim 20, whereby~~ the third potential is provided such that the plurality of charged particle beams impinge on the specimen with an energy corresponding to maximal 5 kV; and

~~whereby~~ the second potential is provided such that the plurality of charged particle beams are accelerated to an energy at least a ~~factor of 5~~ times higher than the energy on impingement on the specimen.

22. (Currently Amended) Method of claim 20, wherein ~~according to any of claims 20 to 21~~ further comprising ~~the following steps:~~

providing a first vacuum in a first region between the emitter array and the electrode unit;

providing a second vacuum in a second region between the electrode unit and the specimen; and

wherein ~~whereby~~ the pressure in the first vacuum is at least a factor of 10 lower than the pressure in the second vacuum.

23. (Currently Amended) Method of claim 20, according to any of claims 20 to 22  
further comprising ~~the following steps~~:

deflecting the plurality of charged particle beams.